

RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2851

00862.022246

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Kazunori IWAMOTO et al.	: Examiner: H. Nguyen
Razuloli IV Alviolo et al.	: Group Art Unit: 2851
Application No.: 09/866,600)
Filed: May 30, 2001	: Confirmation No.: 4961
For: STAGE APPARATUS WHICH SUPPORTS) August 6, 2004
INTERFEROMETER, STAGE POSITION MEASUREMENT METHOD, PROJECTION	:
EXPOSURE APPARATUS, PROJECTION	<i>)</i> :
EXPOSURE APPARATUS MAINTENANCE)
METHOD, SEMICONDUCTOR DEVICE	:
MANUFACTURING METHOD, AND SEMICONDUCTOR MANUFACTURING FACTORY)

Mail Stop AF

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

1.10:

AMENDMENT AFTER FINAL REJECTION

In response to the final Official Action dated May 7, 2004, please amend the above-

identified application as follows, pursuant to 37 C.F.R. § 1.116: